

GP #1756  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of

Francis KO et al.

Application No. 09/894,230

Filed: June 27, 2001

For: APPARATUS AND METHOD FOR ARGON  
PLASMA INDUCED ULTRAVIOLET LIGHT  
CURING STEP FOR INCREASING SILICON-  
CONTAINING PHOTORESIST SELECTIVITY



7/16/02  
#2 (Rescind  
Letter)  
Examiner: Not Assigned

Art Unit: 1756

Docket No. LAM2P257

Date: June 19, 2002

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I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on June 19, 2002.

Signed:

Diane Schwanbeck

REQUEST TO RESCIND PREVIOUS NONPUBLICATION REQUEST

Commissioner for Patents  
Washington, D.C. 20231

Sir:

I hereby rescind the previous request that the above-identified application not be published under 35 U.S.C. § 122(b)(2)(B)(ii).

Respectfully submitted,  
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